	Hits	Search Text	DBs
2	5	insulat\$4 or SiO or Si\$2N\$3) same (conductive or gate or (float\$4 near9 gate)) same	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
5	5	(non\$4volatile near22 memory near22 cell) and (IC or (integrat\$4 near9 circuit\$4)) and ((substrate or workpiece or wafer) same (dielectric or insulat\$4 or SiO or Si\$2N\$3) same (conductive or gate or	US-PGPUB; USPAT; EPO; JPO; DERWENT;
6	21	(IC or (integrat\$4 near9 circuit\$4)) and ((substrate or workpiece or wafer) same (dielectric or insulat\$4 or SiO or Si\$2N\$3) same (conductive or gate or (float\$4 near9 gate)) same (expos\$4 or etch\$4 or mask\$4 or pattern\$4)) and redestal and ((word near9 line)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB

	Hits	Search Text	DBs
7	2	(float\$4 near9 gate)) same (expos\$4 or etch\$4 or mask\$4 or	US-PGPUB; USPAT; EPO;
8	3	same (conductive or gate or (float\$4 near9 gate)) same (expos\$4 or etch\$4 or mask\$4 or	US-PGPUB; USPAT; EPO; JPO;

	Hits	Search Text	DBs
9	5	(float\$4 near9 gate)) same (expos\$4 or etch\$4 or mask\$4 or pattern\$4)) and ((word near9	US-PGPUB; USPAT; EPO;
10	6	(float\$4 near9 gate))) and ((word near22 line) or (conductive near22 (pattern or	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB

	Hits	Search Text	DBs
11	6	((word near22 line) or (conductive near22 (pattern or	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
12	531	(integrat\$4 near9 circuit\$4)) and non\$4volatile and (memory	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
13	214	and non\$4volatile and (memory near16 cell) and (word near12 line) and (conduct\$3 near16	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB
14	106	near16 cell) and (word near12 line) and (conduct\$3 near16	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB